

Semitool SRD-880S Spin Rinse Dryer User Manual



Coral Name: <none>
Model: Semitool SRD-880S
Location: Nanofab, Building 215, Room B102
Contact: nanofab_wetchem@nist.gov
Version: 1.0

Description:

- Dual Stack Front-Loading Spin Rinse Dryer (SRD)
- Manufacturer: Semitool, Kalispell, MT, ph: 406-752-2107
- Resistivity Monitors (RM-20)
- Emergency Off Power (EMO)
- Capable of processing up to 8"/200mm wafers
- Single Bolt Rotor Design

Restrictions:

- CMOS or electronic processing only!
- No metal tweezers or cassettes.
- No loose pieces allowed in Spin Rinse Dryer during operation.
- All masks, wafers, and wafer holders must be secured before start.
- No outside holders or boats. Use only those provided from within the lab.
- No unauthorized projects or individuals.
- Do not process wafers or masks that have any metal on them.
- Failure to follow procedures can and will result in contamination that will ruin your experiment and ruin the experiments of everybody after you.
- Sample size: up to 8"/200mm wafers
- Failure to follow the proper operating instructions or correct safety procedures can lead to losing access privileges.

Safety and Required Personal Protective Equipment (PPE):

- Any and all items being placed within the Spin Rinse Dryer must be secured.
- At such high speeds, loose items become projectiles and pose a considerable safety risk.
- Wait for the rotor to come to a complete stop before loading or unloading samples, and before opening SRD door.
- If the sized rotor that you are looking for is not located within the SRD, contact a NanoFab staff member. **Do Not Change the Rotor on Your Own!**

Process:

- Complete drying of wafers and masks without residual water marks.
- High RPM spinning coupled with deionized water sprays, concluding with a nitrogen dry stage.

Operation:

Power On:

1. On the panel above the top most door of the spin rinse dryer, press the “POWER ON” button.
2. Leave system ON, even after your process.

Power Off:

1. Press the large red “EMO” button.
2. Leave system ON, even after process.
3. Only press the “EMO” button in case of an emergency stop of the machine is necessary.

Running the Spin Rinse Dryer (SRD):

1. Ensure that the proper sized rotor is installed within the SRD. If not, contact a NanoFab staff member to install it. **Do Not Change the Rotor on Your Own!**
2. Make certain that all items wished to be dried are properly secured within the wafer boat.
3. Place the wafer boat with its H-Bridge facing towards the back of the SRD inside of the dryer.
4. Close the SRD door and ensure that it is completely closed.
5. Press and hold the green “ON/RESET” button located at the bottom right hand corner of the door until the SRD initiates.
6. When processes are complete, open door and remove all items.
7. Return door to closed position when finished with the SRD.

Things to Remember:

1. CMOS or electronic processing only!
2. Any and all rotor changes should be completed by NanoFab staff members.
3. No small or loose items are permitted within the Spin Rinse Dryer.
4. Only press the “EMO” (Emergency Off) button in case of actual emergency stop of the machine is required. Otherwise, leave the SRD on after drying process.
5. If you have any questions, or are not exactly sure what you are doing throughout the use of this equipment, stop and find a NanoFab staff member.